	Application No.	Applicant(s)
	10/785,980	KATSUMATA ET AL.
Notice of Allowability	Examiner	Art Unit
	Jermaine Jenkins	2855
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to the interiew with applicant's representative on 7/19/05.		
2. The allowed claim(s) is/are <u>2-13</u> .		
3. The drawings filed on <u>26 February 2004</u> are accepted by the Examiner.		
4.		
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 02262004 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material 	6. ☑ Interview Summary Paper No./Mail Da 8), 7. ☑ Examiner's Amenda	te .

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EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Atty. David Posz on 7/19/05.

The application has been amended as follows:

Claim 1 is cancelled.

In regards to claim 2, line 1, delete "The sensor according to claim 1," and insert the following in its place - - A semiconductor pressure sensor comprising: a semiconductor substrate having a diaphragm for receiving pressure and a bridge circuit for detecting distortion of the diaphragm corresponding to the pressure, wherein the bridge circuit includes a pair of first a pair of second gauge resistors, wherein the first gauge resistors are disposed on a center gauge resistors and of the diaphragm, and the second gauge resistors are disposed on a periphery of wherein the diaphragm, and each first gauge resistor has a first resistance, which is larger than a second resistance of each second gauge resistor. - -

In claim 8, line 1, delete "claim 1", insert the term - - claim 2 - -.

2. The following is an examiner's statement of reasons for allowance. The prior art does not disclose or suggest a semiconductor pressure sensor comprising the bridge circuit having a predetermined ratio of resistance between the second resistance and the first resistance, wherein the diaphragm has another predetermined ratio of thermal stress between a second thermal stress to be applied to the second gauge resistor and a first thermal stress to be applied to the first gauge resistor in a case where a thermal stress is applied to the substrate, and wherein the predetermined ratio of resistance is equal to the predetermined ratio of thermal stress.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

- 3. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.
 - U.S. Patent 6,422,088 (Oba et al) Sensor Failure or Abnormality
 Detecting System Incorporated in a Physical or Dynamic Quantity
 Detecting Apparatus
 - U.S. Patent 5,419,199 (Araki) Semiconductor Device Having a Stress
 Transducer Driven by a Temperature Compensating Reference Voltage
 Source

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U.S. Patent 5,343,755 (Huss) – Strain Gage Sensor with Integral
 Temperature Signal

- U.S. Patent 5,289,721 (Tanizawa et al) –Semiconductor Pressure Sensor
- U.S. Patent 5,253,532 (Kamens) Temperature Compensated Pressure
 Transducer with Digital Output for Low Voltage Power Supply
- U.S. Patent 5,191,798 (Tabata et al) Pressure Sensor
- U.S. Patent 5,167,158 (Kamachi et al) Semiconductor Film Pressure
 Sensor and Method of Manufacturing Same
- U.S. Patent 5,097,841 (Moriunchi et al) Disposable Pressure Tranducer
 and Disposable Pressure Transducer Apparatus
- U.S. Patent 4,813,272 (Miyazaki et al) Semiconductor Pressure Sensor
- U.S. Patent 4,777,826 (Rud, Jr. et al) Twin Film Strain Gauge System

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Jermaine Jenkins whose telephone number is 571-272-2179. The examiner can normally be reached on Monday-Thursday 7am-530pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Edward Lefkowitz can be reached on 571-272-2180. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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